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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
POWER OF ATTORNEY

Docket No.
16159.027001; P6420

Name of Applicant: SUN MICROSYSTEMS, INC.
Address of Applicant: 4150 Network Circle
Santa Clara, CA 95054

Title: RATING APPARATUS AND METHOD FOR EVALUATING BUGS
Serial No., if Any: 09/970,281
Filed: October 3, 2001

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TO THE ASSISTANT COMMISSIONER FOR PATENTS

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The Assistant Commissioner for Patents
Washington, D.C. 20231

Honorable Sir:

Technology Center 2600

I hereby appoint:

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as principal attorneys to prosecute this application and to transact all business in the Patent and Trademark Office connected therewith.

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Dated:

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